



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants: Yong-Pil Han et al.

Serial No.: 09/498,303

Filed: February 4, 2000

For: HF Vapor Phase Wafer Cleaning and Oxide Etching

Confirmation No. 8629

Group Art Unit: 1763

Examiner: T. Dang

COMMISSIONER FOR PATENTS

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I hereby certify that this correspondence is being deposited on the date shown below with the United States Postal Service with sufficient postage as first class mail, under 37 CFR 1.8(a), in an envelope addressed to: Commissioner For Patents, P.O. Box 1450, Alexandria, VA 22313-1450

Yong-Pil Han
November 20, 2003

AMENDMENT

This is in response to the Examiner's Action mailed May 21, 2003.

A petition for three-month extension of time accompanies this amendment.

Please amend the above-identified application as follows:

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks/Arguments begin on page 5 of this paper.